

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No. : 10/549,251
Applicant : Yuichiro Sasaki et al.
Filed : September 13, 2005
Title : "BEAM CURRENT MEASURING APPARATUS AND BEAM
CURRENT MEASURING METHOD USING THE SAME"

Confirmation No. : TBD
TC/A.U. : TBD
Examiner : TBD

Customer No. : 052054
Docket No. : 38771

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

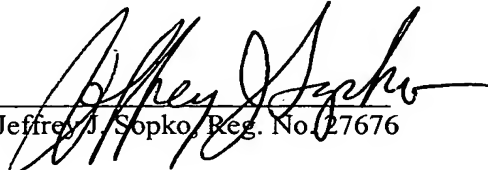
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Sir/Madam:

In accordance with 37 C.F.R. § 1.98, applicant is submitting herewith Form PTO-1449 listing references for consideration by the Examiner. Also submitted herewith is a legible copy of each reference listed.

If there are any fees resulting from this communication, please charge said fees to our Deposit Account No. 16-0820, Order No. 38771.

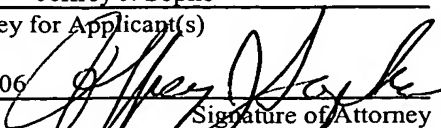
Respectfully submitted,
PEARNE & GORDON LLP

By: 
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February 20, 2006

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Mail Stop PCT, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on the date indicated below.

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| Jeffrey J. Sopko |
| Name of Attorney for Applicant(s) |
| February 20, 2006 |
| Date |
|  Signature of Attorney |

| | | | |
|---|--|---|---------------------------------|
| Form PTO-1449 | U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE | ATTY. DOCKET NO. 38771 | SERIAL NO. 10/549,251 |
| SUPPLEMENTAL INFORMATION DISCLOSURE CITATION BY APPLICANT (USE SEVERAL SHEETS IF NECESSARY) | | APPLICANT: Yuichiro Sasaki et al. | |
| | | FILING DATE: September 13, 2005 | GROUP ART UNIT: TBD |

U.S. PATENT DOCUMENTS

| Examiner Initial | | Document No. | Date | Name | Class | Subclass | Filing Date if Appropriate |
|------------------|---|--------------|------|------|-------|----------|----------------------------|
| | A | | | | | | |
| | B | | | | | | |
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FOREIGN PATENT DOCUMENTS

| | | Document No. | Date | Country | Class | Subclass | Translation |
|--|---|--------------|------|---------|-------|----------|-------------|
| | L | | | | | | |
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| | P | | | | | | |
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OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

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|---|--|
| R | Tanabe, "A Cryogenic Current-Measuring Device with Nano-Ampere Resolution at the Storage Ring TARN II", 09/1998, Pages 455-464 |
| S | Hao et al., "HTS Flux Concentrator For Non-Invasive Sensing Of Charges Particle Beams", 06/2001, Pages 469-470 |
| T | |

Examiner:

Date Considered

*Examiner: Initial if reference considered, regardless of whether citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.